



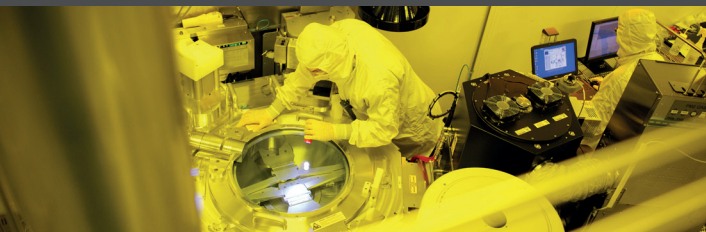
MEMS

Discover our capabilities

C2MI MEMS laboratory has class 10 (ISO 4) cleanrooms. The infrastructure is suitable for the micro-machining of surface layer as well as for silicon. C2MI features production lines for fabrication and wafer level packaging of MEMS on 200mm wafer.

Our processes

- Thin film deposition
- Lithography
- Wet etching
- Dry etching
- Photoresist stripping
- Bonding
- Debonding
- Chemical/mechanical polishing
- Plating
- Metrology
- Thermal treatment
- Surface micromachining





The Centre

C2MI is the largest research and development centre in microelectronic across Canada. Offering state-of-the-art equipment dedicated mainly to advanced packaging and micro-electromechanical systems (MEMS), the Centre also welcomes together more than 250 scientists in research and development (R & D).

« Collaboration and synergy among our partners promote rapid commercialization of advanced prototypes. »



MiQro Innovation
Collaborative Centre

45 boulevard de l'Aéroport
Bromont, QC, Canada, J2L 1S8
450-534-8000
www.c2mi.ca

